Application/Control No. 10/088,206 Examiner Gail Verbitsky Applicant(s)/Patent Under Reexamination DEWAELE, LUC Art Unit Page 1 of 1

Notice of References Cited

U.S. PATENT	DΩ	CL	JM	EN	T:
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*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	Α	US-6220750	04-2001	Palti	374
	В	US-5001925	03-1991	Turek	73
	С	US-5318077	06-1994	Yamashita	139
	D	US-4336708	06-1982	Hobgood et al.	73
	Ε	US-5281793	01-1994	Gavin et al.	219
_	F	US-3559726	02-1971	Menasoff	73
	G	US-3926053	12-1975	Schurrer et al.	324
	Н	US-5939978	08-1999	Kyrtsos	340
	ı	US-6000844	12-1999	Cramer et al.	374
-	J	US-5123752	06-1992	Paz-Pujalt et al.	374
	К	US-4674326	06-1987	Reinecke	73
	L	US-4046990	09-1977	White	219
	M	US-5352038	10-1994	Schmidt et al.	374

FOREIGN PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N	JA0209329	09-1986	JA		374
	0					
	Р					
	Q					
	R					•
	S					
	Т					

NON-PATENT DOCUMENTS

	HON-FATERI BOSSMERIO					
*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)				
	U					
	٧					
	w					
	х					

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).) Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.